

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of

Tuqiang Ni et al.

Application No.: 09/788,365

Filed: February 21, 2001

For: GAS INJECTION SYSTEM FOR  
PLASMA PROCESSING

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)  
) Group Art Unit: 1792  
)  
) Examiner: R. Zervigon  
) Confirmation No.: 3359  
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)  
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**FOURTH INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. §1.56, Applicant hereby submits a translation of an Official Action mailed February 12, 2010 for a corresponding Japanese application. Pursuant to 37 C.F.R. §1.98, a copy of each of the non-U.S. documents not previously cited is enclosed.

I, the undersigned, hereby certify that each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that these documents be made of record and placed in the file.

Respectfully submitted,

BUCHANAN INGERSOLL & ROONEY PC

Date April 1, 2010

By: 

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